Search Notes			

Application/Control	No
10/660,306	

Applicant(s)/Patent under Reexamination	
LIU, HEBEN	

10/660,306 Examiner

Christopher K. Agrawal

Art Unit

SEARCHED				
Class	Subclass	Date	Examiner	
29	890.032	5/11/2006	СКА	
	890.045	5/11/2006	СКА	
	890.046	5/11/2006	CKA	
	890.05	5/11/2006	CKA	
	726	5/11/2006	CKA	
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INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	
see	attached	5/11/2006	CKA	
search	history	5/11/2006	СКА	

SEARCH NO (INCLUDING SEARCH)
	DATE	EXMR
see attached EAST workspace for search history	5/11/2006	CKA
consulted Examiner Compton regarding field of search	5/11/2006	CKA
updated search and consulted 10/318591	5/11/2006	СКА